



## TYPICAL TYTAN FURNACE PROCESSES

### ATMOSPHERE

HIGH TEMP ANNEAL

METAL ANNEAL

WET OXIDATION

-BUBBLER

-PYROGENIC

-DRIP FEED FLASH VAPORIZATION

DRY OXIDATION

SOLID SOURCE DOPING

"P" Type

"N" Type

LIQUID SOURCE DOPING

-POCl<sub>3</sub>

-BBr<sub>3</sub>

SINTERING

CARBON NANOTUBES

GRAPHENE

### LPCVD

SILICON NITRIDE /LOW STRESS

HIGH TEMPERATURE OXIDE

POLYSILICON (DOPED/UNDOPED)

LOW TEMPERATURE OXIDE

PSG

BPSG

SILICON NANOWIRES

TEOS

SiGe POLYCRYSTALLINE NANOWIRES